

# Claims

- [c1] 1. A semiconductor device, the semiconductor device comprising:  
a bump pad and a fuse pad over a wafer, wherein the fuse pad includes a burnt fuse pad having a gap for electrical isolation;  
a dielectric layer, disposed substantially above the burnt fuse pad and filling the gap; and  
a bump structure, disposed on the bump pad.
- [c2] 2. The semiconductor device of claim 1, further comprising a passivation layer, which exposes the bump pad and a portion of the burnt fuse pad, wherein the dielectric layer is over the passivation layer, covers the exposed portion of the burnt fuse pad, and fills the gap.
- [c3] 3. The semiconductor device of claim 1, wherein the dielectric layer includes one selected from the group consisting of Benzocyclobutene (BCB), Poly-Imide (PI), Nitride,  $\text{SiN}_3$ , Spin-On Glass (SOG), Spin-On Dielectric (SOD),  $\text{SiO}_x$ , and  $\text{SiO}_2$ .
- [c4] 4 The semiconductor device of claim 1, wherein the bump structure includes:

an under ball metallurgy (UBM) layer to cover the exposed bump pad; and  
a bump on the UBM layer.

- [c5] 5. The semiconductor device of claim 1, wherein the semiconductor device comprises a memory device.
- [c6] 6. A protection structure for preventing a burnt fuse pad from re-electrical connection in a semiconductor device, the semiconductor device includes a bump pad, a bump structure on the bump pad, and a fuse pad over a wafer, wherein the fuse pad includes the burnt fuse pad having a gap for electrical isolation, the protection structure comprising:  
a dielectric layer, disposed substantially above the burnt fuse pad and filling the gap of the burnt fuse pad.
- [c7] 7. The protection structure of claim 6, wherein the dielectric layer includes one selected from the group consisting of Benzocyclobutene (BCB), Poly-Imide (PI), Nitride,  $\text{SiN}_3$ , Spin-On Glass (SOG), Spin-On Dielectric (SOD),  $\text{SiO}_x$ , and  $\text{SiO}_2$ .
- [c8] 8. The protection structure of claim 6, further comprising a passivation layer, which exposes the bump pad and a portion of the burnt fuse pad, wherein the dielectric layer is over the passivation layer, covers the exposed

portion of the burnt fuse pad, and fills the gap.

- [c9] 9. The protection structure of claim 6, wherein the semiconductor device includes a memory device.